

**Amendments to the Claims:**

The following listing of the claims will replace all prior versions, and listings, of the claims in the application:

1. (Original) Substrate treatment equipment having,  
a substrate treatment chamber,  
a substrate holder that can be inserted into the substrate treatment chamber and holds substrates in a multistage manner in a substantially vertical direction,  
a substrate transfer unit for transferring the substrates into the substrate holder,  
and  
a sensing device for sensing a holding condition of the substrates held in the substrate holder; characterized by including,  
a control device that, in transfer of the substrates, senses the holding condition of the substrates using the sensing device, and controls the substrate transfer unit such that substrates other than a substrate which was determined to be in an abnormal substrate holding condition are transferred by the substrate transfer unit.
2. (Original) The substrate treatment equipment according to claim 1, characterized in that the control device controls the substrate transfer unit such that substrates other than the substrate determined to be abnormal and at least one of substrates held on and under the substrate determined to be abnormal are transferred by the substrate transfer unit.
- 3-4. (Canceled)